AIBT ISTAR – High Current Ion Implanter System

AREA	ITEM	DESCIPTION	Q'ty
End	Wafer Size	300mm	
Station	Load Port	TDK	*4 SET
Vacuum	Transfer Module -DP	BOC	NOT INCULD
	Process Transfer Module -DP	BOC	NOT INCULD
	Process Transfer Module -CP	CIT 10F	2
	SOURCE -TP	STP-A2203	1
	SOURCE -DP	BOC	NOT INCULD
	Beam Line – TP	STP-451 C	1
Gas Box	GAS 0	Ar	FAC
	GAS 1	Ar	HP
	GAS 2	N2	HP
	GAS 3	BF3	SDS
	GAS 4	BF3	SDS
	GAS 5	AsH3	SDS
	GAS 6	PH3	SDS
SOURCE	SOURCE HEAD	SET	1
	Extraction Electrode	SET	1
Beam	P SHOW	SET	1

Line	Decel Electrode	SET	1
DISK	Batch Disk	Clamp type	13 PAD